Workshop »Coatings for Optics and Optical Components«

Coatings for EUV-Lithography Optics

Dr. Hartmut Enkisch

Carl Zeiss SMT GmbH, Oberkochen

hartmut.enkisch@zeiss.com

We will explain the working principle of EUV-Lithography tools. From the key performance indices, we will derive the requirements to the optics. We will show how the development of optical coatings for 13.5 nm wavelength is enabling the industrialization of EUV-Lithography.